10/688839

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Delgado et al.

Attorney Docket No.: KLA1P083/P1039

Patent: 7,138,640 B1

Issued: November 21, 2006

Title: METHOD AND APPARATUS FOR PROTECTING SURFACES OF OPTICAL COMPONENTS

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on August 16, 2007 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: _____

Aurelia M. Sanchez

REQUEST FOR CERTIFICATE OF CORRECTION OF OFFICE MISTAKE (35 U.S.C. §254, 37 CFR §1.322)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Attn: Certificate of Correction

Dear Sir:

Attached is Form PTO-1050 (Certificate of Correction) at least one copy of which is suitable for printing. The errors together with the exact page and line number where the errors are shown correctly in the application file are as follows:

CLAIMS:

1. In line 3 of claim 4 (column 17, line 18) change "bet" to --between--. This appears correctly in Amendment B as filed on June 23, 2006 on page 7, paragraph 2, line 2, as claim 37.

2. In line 1 of claim 29 (column 19, line 5) change "inspections" to --inspection--. This appears correctly in Amendment B as filed on June 23, 2006 on page 4, paragraph 2, line 1, as claim 20.

3. In line 3 of claim 29 (column 19, line 8) change "in from" to --in front--. This appears correctly in Amendment B as filed on June 23, 2006 on page 4, paragraph 2, line 3, as claim 20.

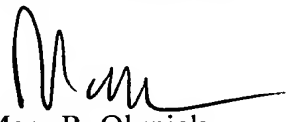
4. In line 12 of claim 31 (column 20, line 17) change "list" to --light--. This appears correctly in Amendment B as filed on June 23, 2006 on page 6, paragraph 1, line 8, as claim 32.

5. In line 16 of claim 31 (column 20, line 21) change "steam" to --stream--. This appears correctly in Amendment B as filed on June 23, 2006 on page 6, paragraph 1, line 11, as claim 32.

Patentee hereby requests expedited issuance of the Certificate of Correction because the error lies with the Office and because the error is clearly disclosed in the records of the Office. As required for expedited issuance, enclosed is documentation that unequivocally supports the patentee's assertion without needing reference to the patent file wrapper.

It is noted that the above-identified errors were printing errors that apparently occurred during the printing process. Accordingly, it is believed that no fees are due in connection with the filing of this Request for Certificate of Correction. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 50-0388 (Order No. KLA1P083).

Respectfully submitted,
BEYER WEAVER LLP



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AUG 23 2007

18. (Original) The system as recited in claim 16 wherein flowing a gas stream in front of the exposed optical surface effectively removes the contaminants in a region proximate the exposed optical surface.

19. Cancelled.

20. (Currently Amended) A gas flow system for an optical inspection system, the gas flow system comprising:

a means for flowing a gas stream in front of an exposed optical surface of the optical inspection system so as to prevent contaminants from adversely effecting the exposed optical surface of the optical inspection system,

~~The system as recited in claim 16~~ wherein the gas stream is routed away from the exposed optical surface substantially parallel to the optical axis of the optical surface.

21. (Original) A system for inspecting substrates, comprising:

an optical subsystem having a front lens; and

a cover disposed between the front lens and the substrate to be inspected, the cover having an opening that allows ultra violet light to pass between the front lens and the substrate to be inspected, the cover defining at least in part a channel within in which a gas stream is created for the purpose of preventing particles from depositing on the front lens.

22. Cancelled.

23. (Previously Presented) An optical inspection system for inspecting a semiconductor surface for defects or other abnormalities thereof, comprising:

an optical subsystem configured to collect light emanating from the semiconductor surface and to direct the collected light to a detector, the optical subsystem including a series of optical components a lens disposed along an optical path, the series of optical components including a front collection lens that is the optical component closest to the semiconductor surface; and

a transparent cover disposed proximately to the front collection lens between the front collection lens and the semiconductor surface to protect the front collection lens from contamination.

31. Cancelled.

32. (Currently Amended) A gas flow system for an optical inspection system, the gas flow system comprising:

a means for flowing a gas stream in front of an exposed optical surface of the optical inspection system so as to prevent contaminants from adversely effecting the exposed optical surface of the optical inspection system,

wherein the optical inspection system includes an optical subsystem having a plurality of optical components aligned along an optical axis, the optical components cooperating to collect light emanating from a sample and to direct the collected light to a detector for the purpose of defect analysis, and wherein the exposed optical surface is from at least one of the optical components of the optical inspection system, and

~~The gas flow system as recited in claim 31~~ wherein the gas stream flows at least in part parallel to the exposed surface.

33. (Previously Presented) The inspection system as recited in claim 1 wherein the planar cover is spaced apart from the optical surface of the optical component along the optical axis such that a gas conduit is created between the cover and the optical surface of the optical component, the gas stream flowing through the gas conduit and through the opening in the cover.

34. (Previously Presented) The inspection system as recited in claim 1 wherein the optical subsystem is disposed inside a housing, and wherein the gas purging system includes a gas source that supplies gas into the housing thereby forming the gas stream, the planar cover cooperating with the housing to enclose the optical subsystem such that the gas stream exits through the opening in the planar cover.

35. (Previously Presented) The inspection system as recited in claim 1 wherein the optical component is a front collection lens that is the optical component of the optical subsystem that is closest to the sample to be inspected.

36. (Previously Presented) The inspection system as recited in claim 35 wherein the planar cover is spaced apart from the optical surface of the front collection lens along the optical axis such that a first gas conduit is created between the cover and the optical surface of the front

collection lens, wherein the planar cover is spaced apart from the surface of the sample to be inspected along the optical axis such that a second gas conduit is created between the planar cover and the surface of the sample to be inspected, and wherein the gas stream flows through the first conduit to the opening and from the opening through the second conduit.

37. (Previously Presented) The inspection system as recited in claim 36 further comprising a transparent cover disposed along the optical axis between the planar cover and the sample to be inspected, the second conduit being created between the planar cover and the transparent cover.

38. (Previously Presented) The inspection system as recited in claim 35 further comprising a transparent cover disposed along the optical axis between the front collection lens and the planar cover, the planar cover being spaced apart from the transparent cover along the optical axis such that a first gas conduit is created between the planar cover and the transparent cover, wherein the planar cover is spaced apart from the surface of the sample to be inspected along the optical axis such that a second gas conduit is created between the planar cover and the surface of the sample to be inspected, and wherein the gas stream flows through the first conduit to the opening and from the opening through the second conduit.

PTO/SB/44 (10-96)
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(Also Form PT-1050)

UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 7,138,640 B1 Page 1 of 1

DATED : November 21, 2006

INVENTOR(S) : Delgado et al.

It is certified that error appears in the above-identified patent and that said Letters Patent are hereby corrected as shown below:

In the Claims:

In line 3 of claim 4 (column 17, line 18) change "bet" to --between--.

In line 1 of claim 29 (column 19, line 5) change "inspections" to --inspection--.

In line 3 of claim 29 (column 19, line 8) change "in from" to --in front--.

In line 12 of claim 31 (column 20, line 17) change "list" to --light--.

In line 16 of claim 31 (column 20, line 21) change "steam" to --stream--.

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